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2814

U.S.S.N. 10/032,353

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Ming-Huan Tsai et al. Group Art Unit: 2814

Serial No.: 10/032,353

Examiner: H.B. Trinh

Filed: 12/21/2001

In Response to Office Action  
Dated: 10/08/2003

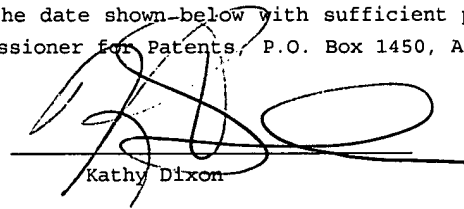
For: A BI-LAYER PHOTORESIST METHOD FOR FORMING HIGH RESOLUTION  
SEMICONDUCTOR FEATURES

Attorney Docket No.: 67,200-567

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450

Date: Jan. 5, 2004

  
Kathy Dixon

RESPONSE TO OFFICE ACTION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 10/08/2003,  
please enter the following amendments and consider the following  
remarks. The Commissioner is hereby authorized to charge Deposit  
Account No. 50-0484 any fee due as a result of this response.